

FORM PTO-1449 (REV. 7-80)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. NIT-207	SERIAL NO.	JCS86 U.S. PTO 09/16/00 07/13/00
<b>LIST OF DOCUMENTS CITED BY APPLICANT</b> <i>(Use several sheets if necessary)</i>				APPLICANT M. ISHIBASHI et al		
				FILING DATE July 13, 2000		
<b>U.S. PATENT DOCUMENTS</b>						
* EXAMINER INITIAL	DOCUMENT	DATE	NAME	CLASS	SUBCLASS	FILING DATE (If Appropriate)
	AA					
	AB					
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<b>FOREIGN PATENT DOCUMENTS</b>						
	DOCUMENT	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO
SEP	AL	11-73906	03/16/99	Japan (with English Abstract)		<input type="checkbox"/> <input type="checkbox"/>
	AM					<input type="checkbox"/> <input type="checkbox"/>
	AN					<input type="checkbox"/> <input type="checkbox"/>
	AO					<input type="checkbox"/> <input type="checkbox"/>
	AP					<input type="checkbox"/> <input type="checkbox"/>
<b>OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)</b>						
SEP	AR	M.A. McCord et al, "Lithography with the Scanning Tunneling Microscope", JOURNAL OF VACUUM SCIENCE AND TECHNOLOGY, Vol. B4, No. 1, Jan/Feb 1986, pp. 86-88.				
SEP	AS	M.A. McCord et al, "Lift-Off Metallization Using Poly (Methylmethacrylate) Exposed with a Scanning Tunneling Microscope", JOURNAL OF VACUUM SCIENCE AND TECHNOLOGY, Vol. B6, No. 1, Jan/Feb 1988, pp. 293-296.				
SEP	AT	A. Majumdar et al, "Nanometer-Scale Lithography Using the Atomic Force Microscope", APPLIED PHYSICS LETTERS, Vol. 61, No. 19, November 1992, pp. 2293-2295.				
EXAMINER <i>Sharon Payne</i>			DATE CONSIDERED <i>29-Aug-2001</i>			
* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.						

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	AP						<input type="checkbox"/> <input type="checkbox"/>
<b>OTHER DOCUMENTS</b> <i>(Including Author, Title, Date, Pertinent Pages, etc.)</i>							
SEP	AR	K. Wilder et al, "Hybrid Atomic Force/Scanning Tunneling Lithography", JOURNAL OF VACUUM SCIENCE AND TECHNOLOGY, Vol. B15, No. 5, Sep/Oct 1997, pp. 1811-1817.					
SEP	AS	M. Ishibashi et al, "Characteristics of Nanoscale Lithography Using AFM with a Current-Controlled Exposure System", JAPANESE JOURNAL OF APPLIED PHYSICS, Vol. 37, 1998, pp. 1565-1569.					
SEP	AT	T.R. Albrecht et al, "Microfabrication of Cantilever Styli for the Atomic Force Microscope", JOURNAL OF VACUUM SCIENCE AND TECHNOLOGY, Vol. A8, No. 4, Jul/Aug 1990, pp. 3386-3396.					
EXAMINER <i>Sharon Payne</i>				DATE CONSIDERED <i>29-Aug-2001</i>			
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	AO					<input type="checkbox"/>	<input type="checkbox"/>
	AP					<input type="checkbox"/>	<input type="checkbox"/>
<b>OTHER DOCUMENTS</b> <i>(Including Author, Title, Date, Pertinent Pages, etc.)</i>							
sel	AR	S. Iijima, "Helical Microtubules of Graphitic Carbon", NATURE, Vol. 354,					
		November 7, 1991, pp. 56-59.					
sel	AS	H. Dai et al, "Nanotubes as Nanoprobes in Scanning Probe Microscopy",					
		NATURE, Vol. 384, November 14, 1996, pp. 147-150.					
	AT						
EXAMINER <i>Sharon Payne</i>				DATE CONSIDERED <i>29-Aug-2001</i>			

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